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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10059701	FILING DATE 01/29/2002	CLASS 438	SUBCLASS 753	GAU 2812	EXAMINER Meckey, T
**APPLICANTS: Kassir Salman;					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>					
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials			ATTORNEY DOCKET NO 212/361		
TITLE : Method of spin etching wafers with an alkali solution					

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NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G
ISSUE FEE Amount Due Date Paid		DRAWING Sheets Drwg. Figs.Drwg. Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner PREPARED FOR ISSUE Application Examiner	
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